

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed: March 12, 2004


For: Method Of Depositing An
Amorphous Carbon Film For Metal
Etch Hardmask Application

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Group Art Unit: 1765

Examiner: Maki A. Angadi

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF TRANSMISSION	
I hereby certify that this correspondence is being electronically transmitted to the U.S. Patent and Trademark Office via EFS-Web to the attention of Examiner Maki A. Angadi, on the date shown below.	
February 27, 2007	
Date	Keith M. Tackett

Dear Sir:

RESPONSE TO OFFICE ACTION DATED NOVEMBER 27, 2006

In response to the Office Action dated November 27, 2006, having a shortened statutory period for response set to expire on February 27, 2007, please enter this response and reconsider the claims pending in the application for the reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.